

my Trom Conductance. & Transfer of p chagn-1 3). Property) · , · · · · · · g na portance. Ch am 10 As io avi = Eonig3 Drift @ => There Should 2 Re Combination cuo orants. Since Unipolas Not be Diffusion no minority Effect Voitage Control => No Low level device No Thermal Theimal Away. Priciples. No Law of Junction No Recombination [were nt Choosent is due to IS INVALIO. 10 Since voitage (ex) I IP

IS (ontrolled by Effect
Field Field Field Field Either free Electrons (or) holes => UNIPOLAR device4).

Proporties ? How can we Impliment Above what to Do 9 田田田田田田 00000 00000 Diff. & Recombined Not be * Should happend *

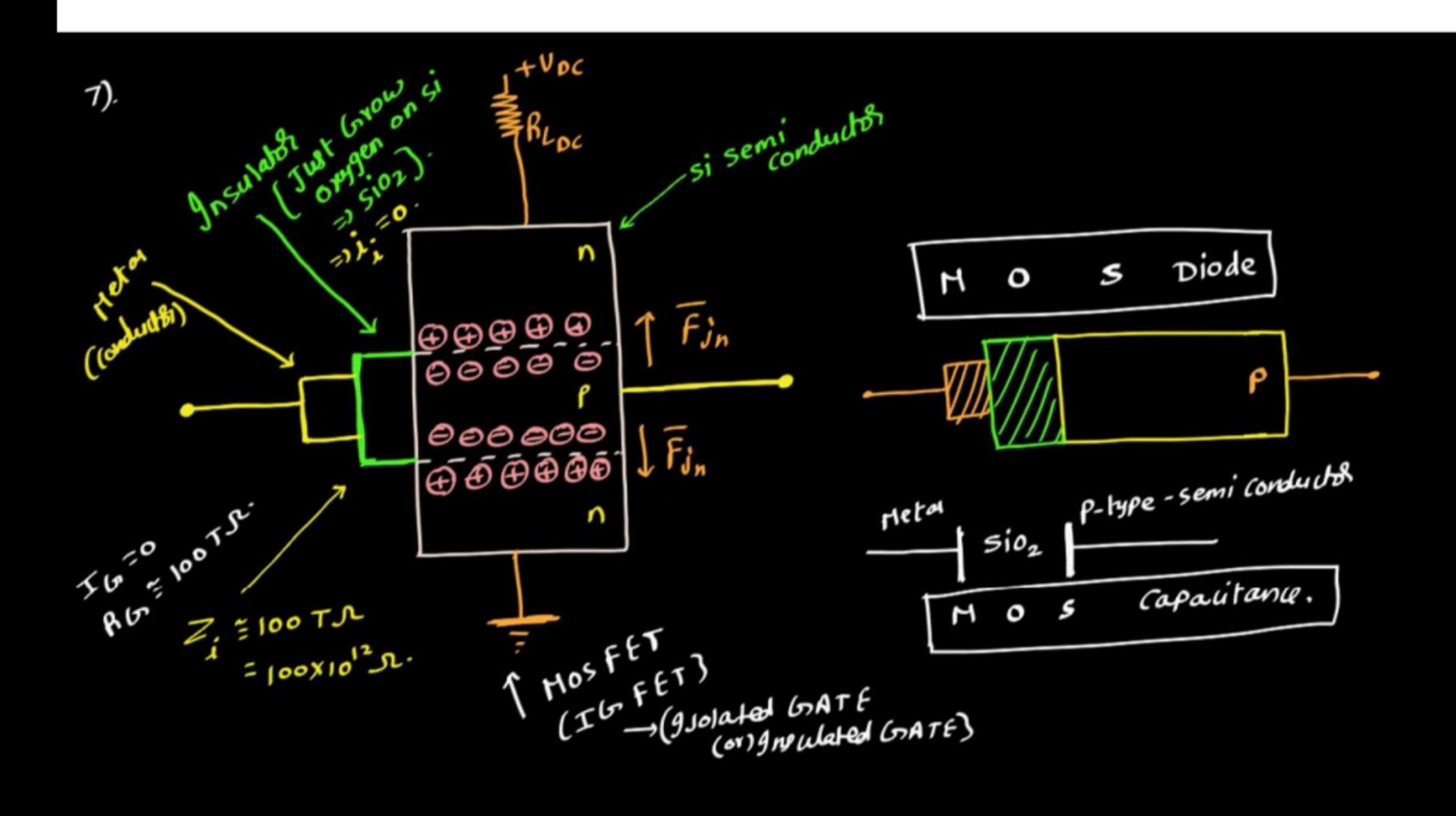
5).

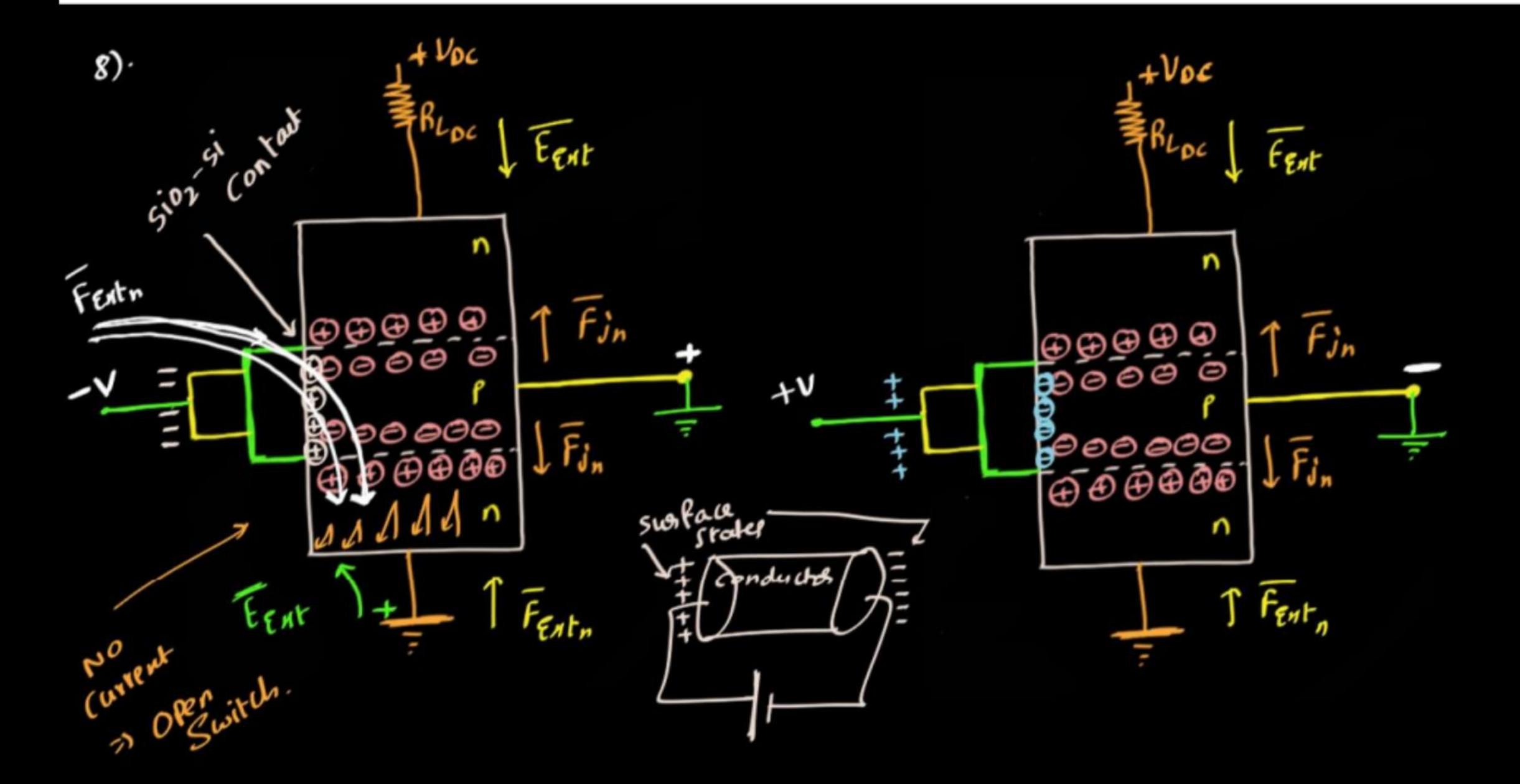
Either ρ (or) nDop heavily.

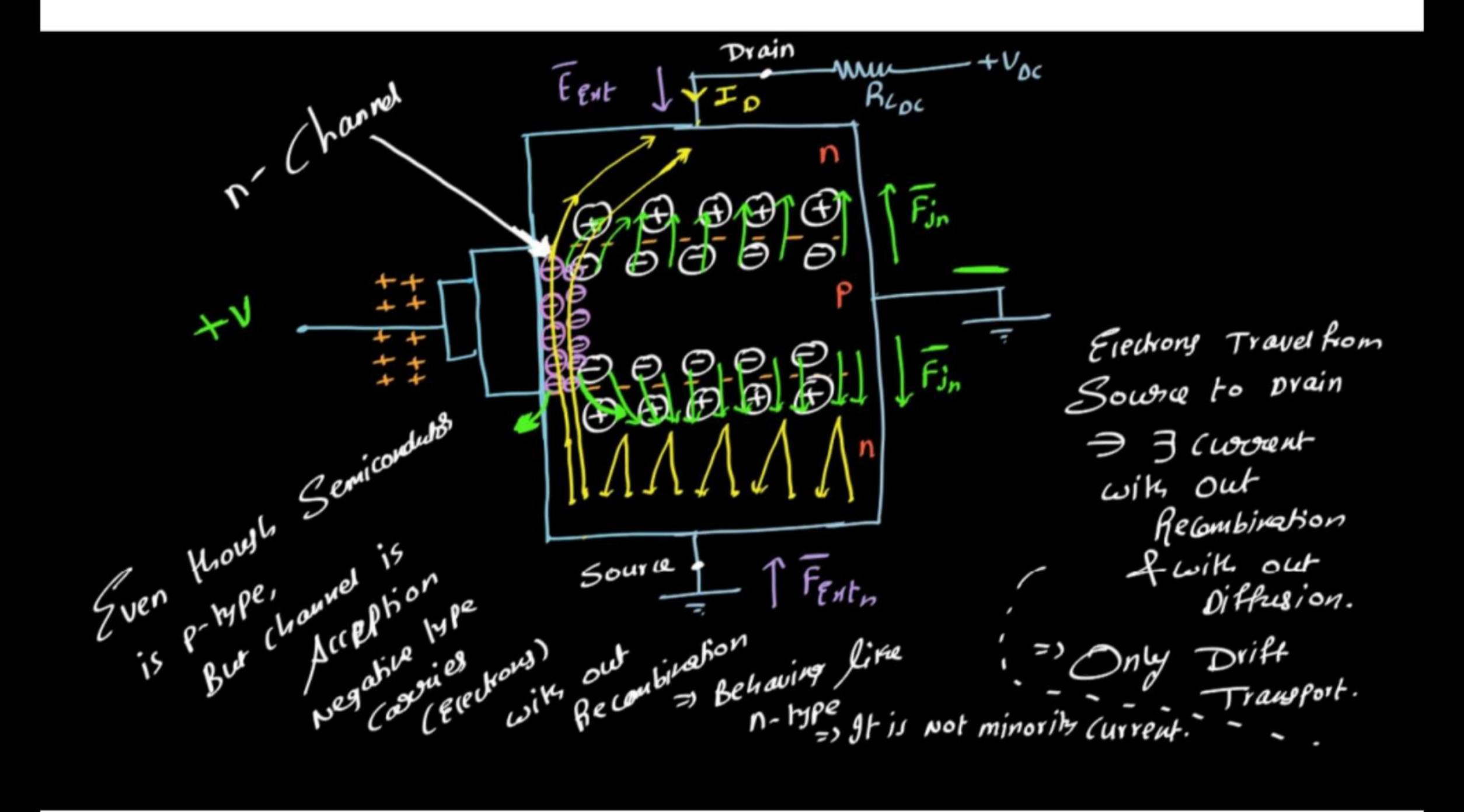
Ly: $V_{bi} = \frac{kT}{q} \log \frac{|N_DN_A|}{n_i^2}$ =) higher Doping =) higher V_{bi} =) higher $\overline{F_i}$.

problem repolved.

-> But No Coopent in the device ----How to
Solve this 9







=> Egt is caused Inversion Mode. 3. i. N-channel - NHOS i.e., Electron Cwornt. The I/P Vol., Controls off woodent. Enhancement Casocies The I/P vol., Controls from of Transport. Carriere (Mobility) from Sowne to Enhancement MosfET. Drain. GIATE.

Jolp & VIIP - Trang Conductance device. .. I/P Terminal

9).

From Above Analysis -

where current is generated

where current is controlled

where Mobility Controlled

where chance of getting

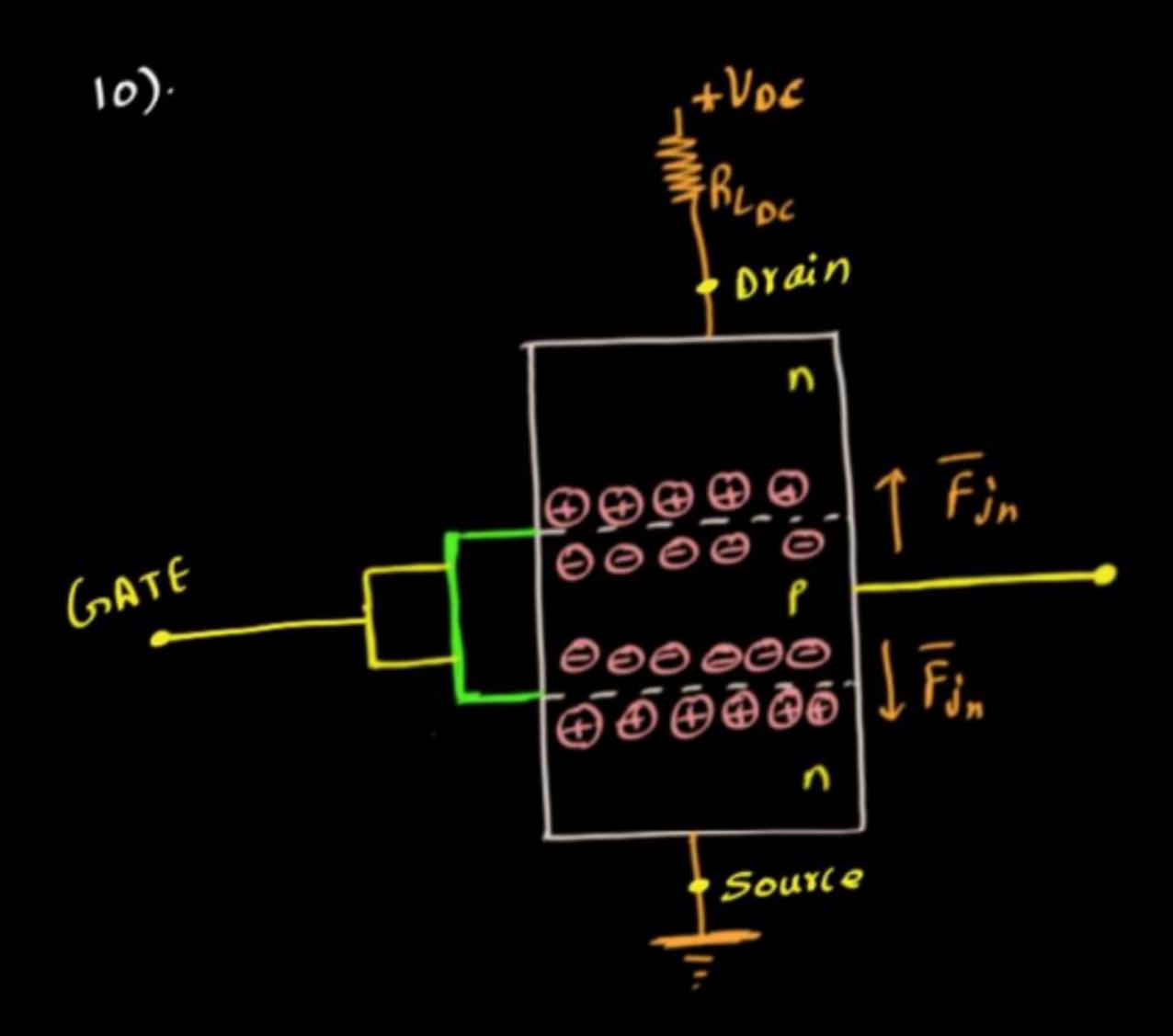
More heat

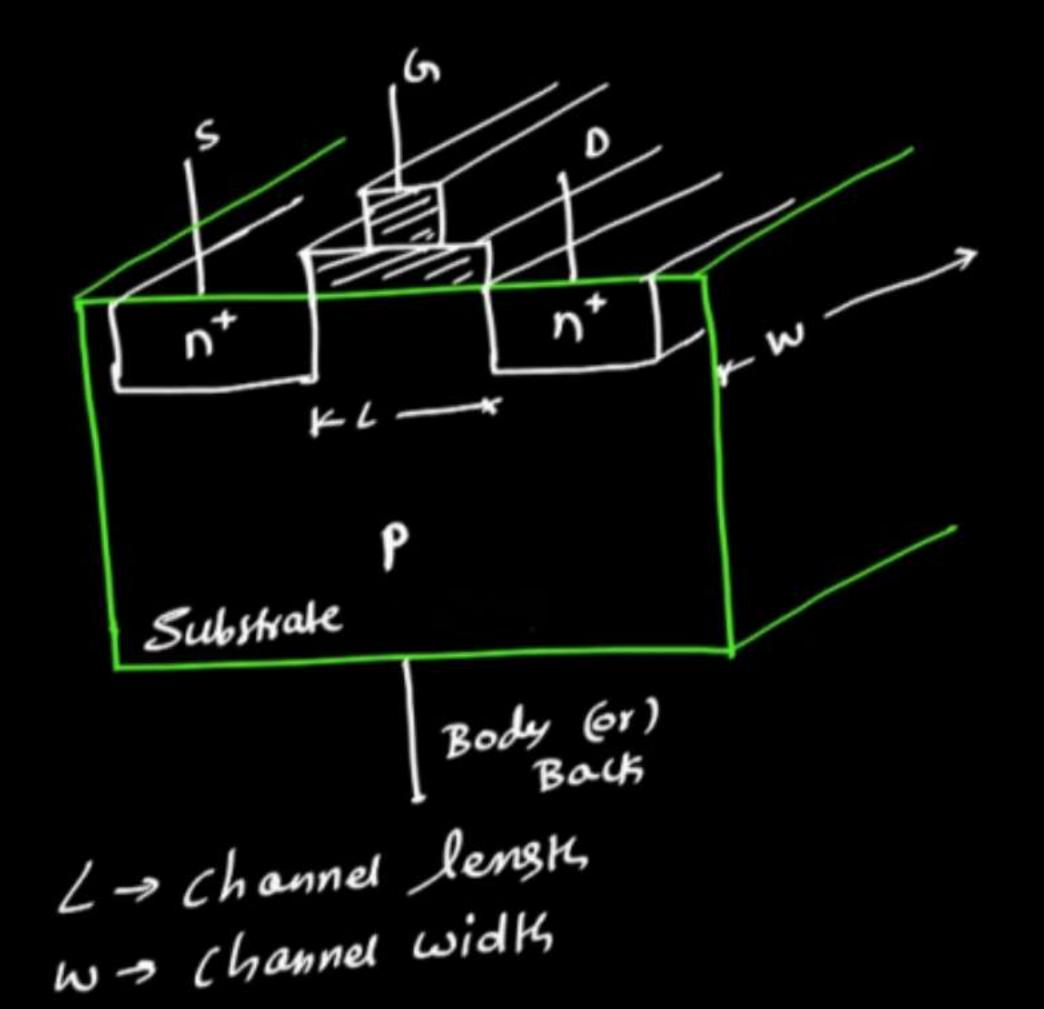
where Inversion Channel

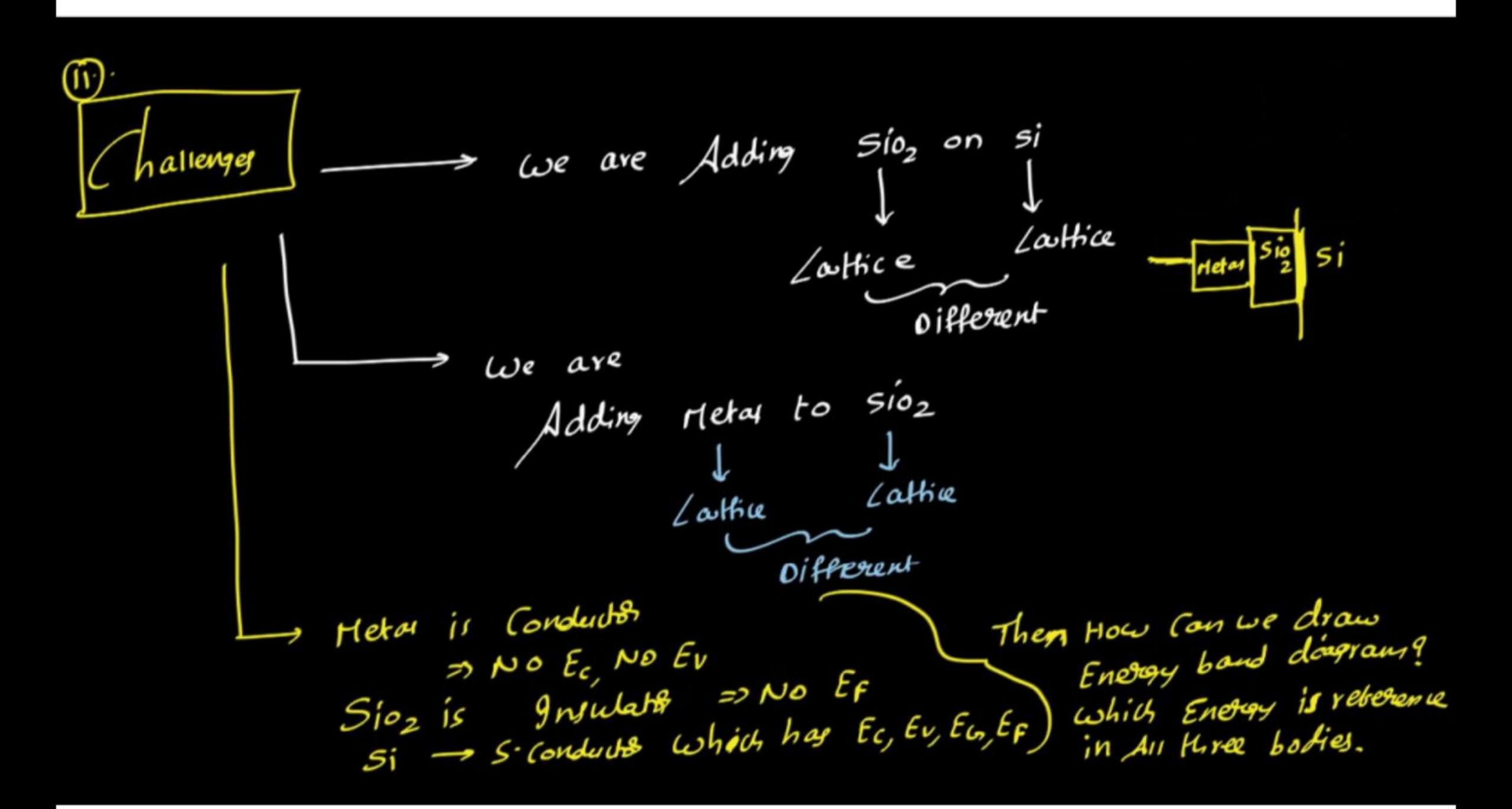
Exist

P-region in
Above
Example

=> Increase He
Size of
P-region
in N-Mos.







The Energy states that Occur @ the Doundaries of the Material (01) Surfaces of the Material - Surface" States.
These Occur because of the Other Material Starting @ the Surface (01) Loundary. Surface States can Act as Traps Which Effect charge Transport in Semiconductors, can influence Land Lending.

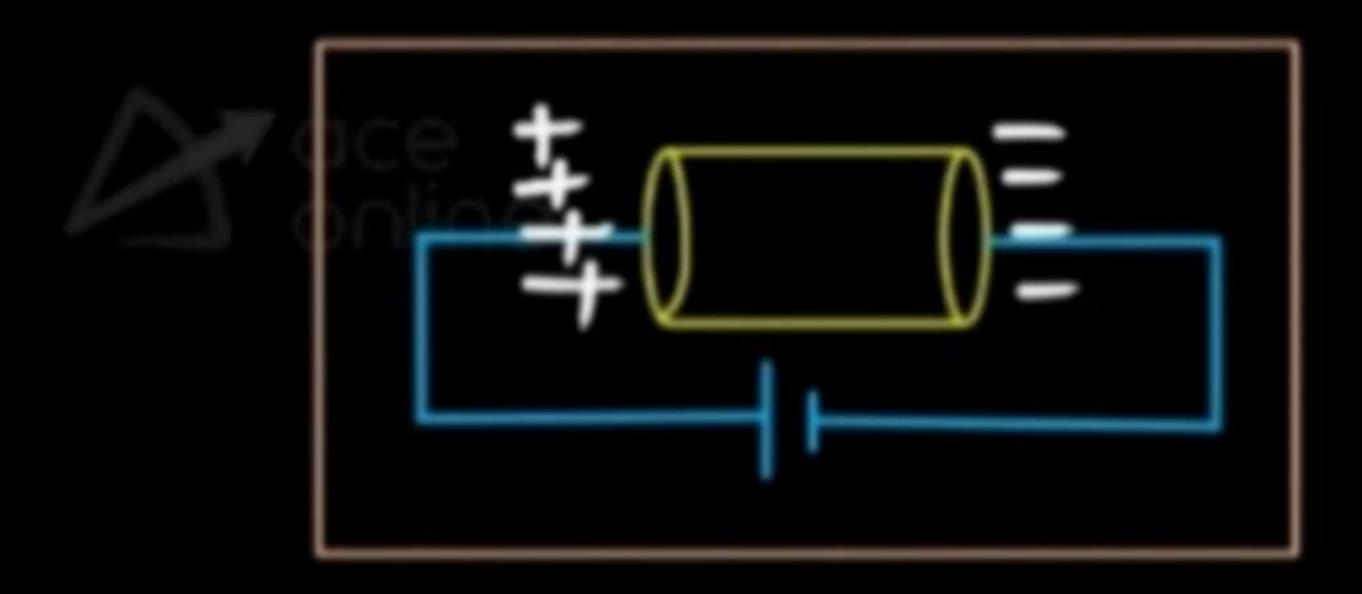
Because Si has different Lattice, Sioz has different Lattice, -> 3 dangling bonds, As In MosfET 3 channel @Interface it selt, 3 Major impact on device Operation. "Surface Passivation techniques can be Used to Greduce density of Surface

EDVAC COMMON Gret. Energy level for Conductory Insulatory & Semiconductors.

\$ - Work Frenchion

X -> Electron Affinity

Also we know a metal always accumulate surface states for metal the (ions) states are outside (surface of metal) inside metal there is e movement only when excited where as for S.C the states are inside the S.C only.



Metal Contact (Metal to 5.c. Contact) -

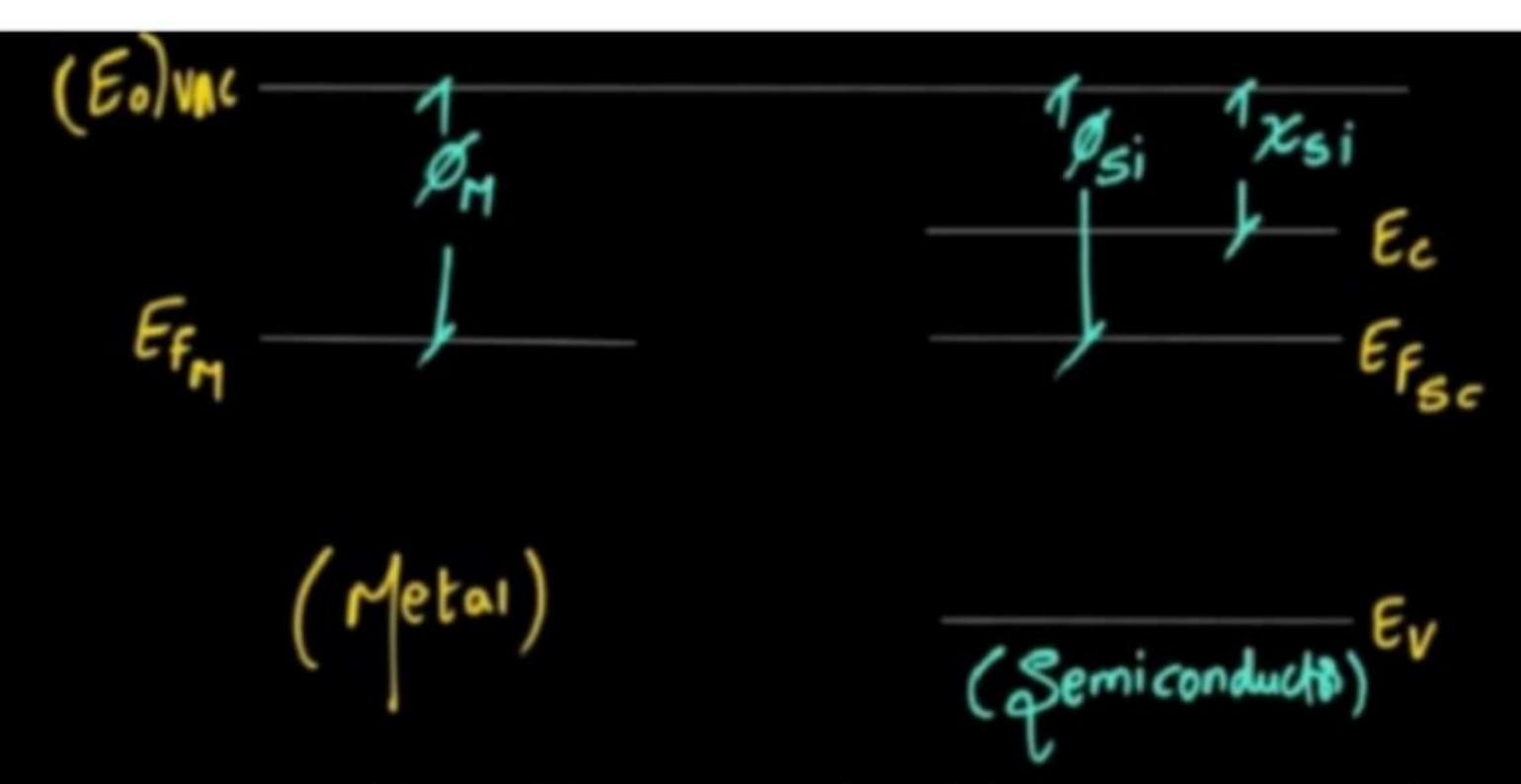
Energy Required Exto Vaccum

Exto Vaccum

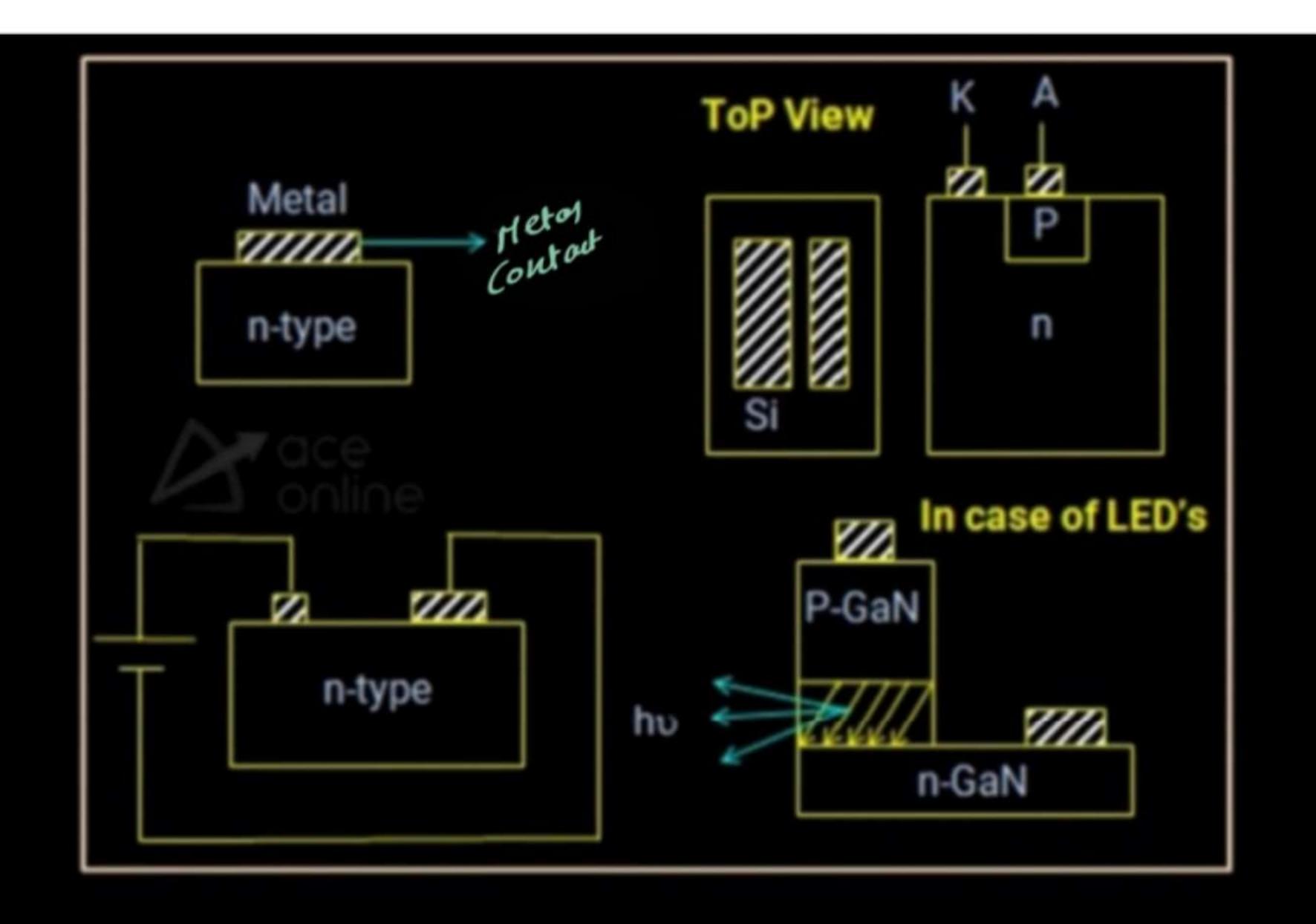
On Exectron Anony function (\$).

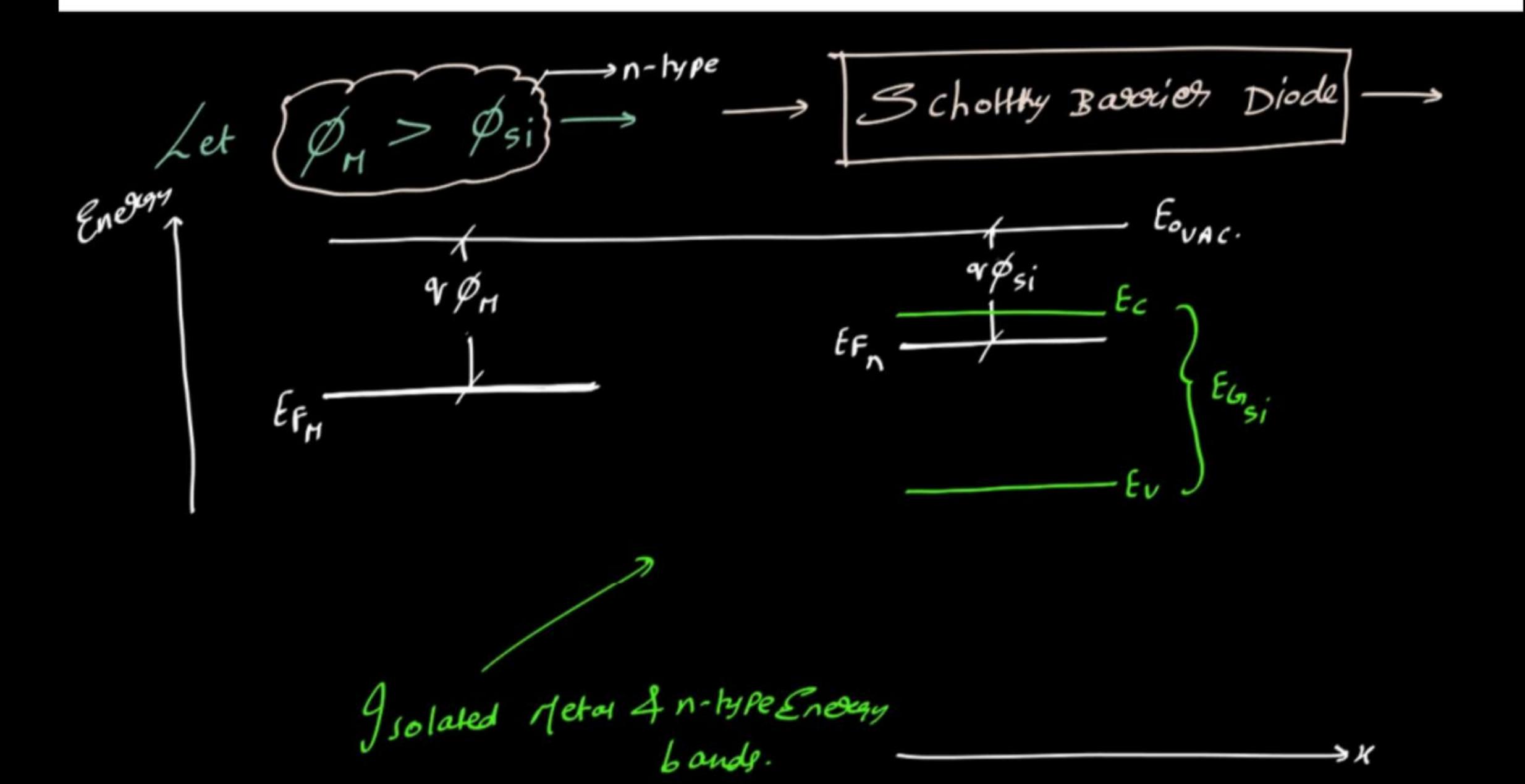
Energy Required from Ecton Expensed on From Ecton Application (X)

For Enample - Let Metal & Semicondules has a Contact. Join Metar & Semiconduter). As Already We KNOW Metal contails are Must if Semiconduls Wanti to Communicate with External World).

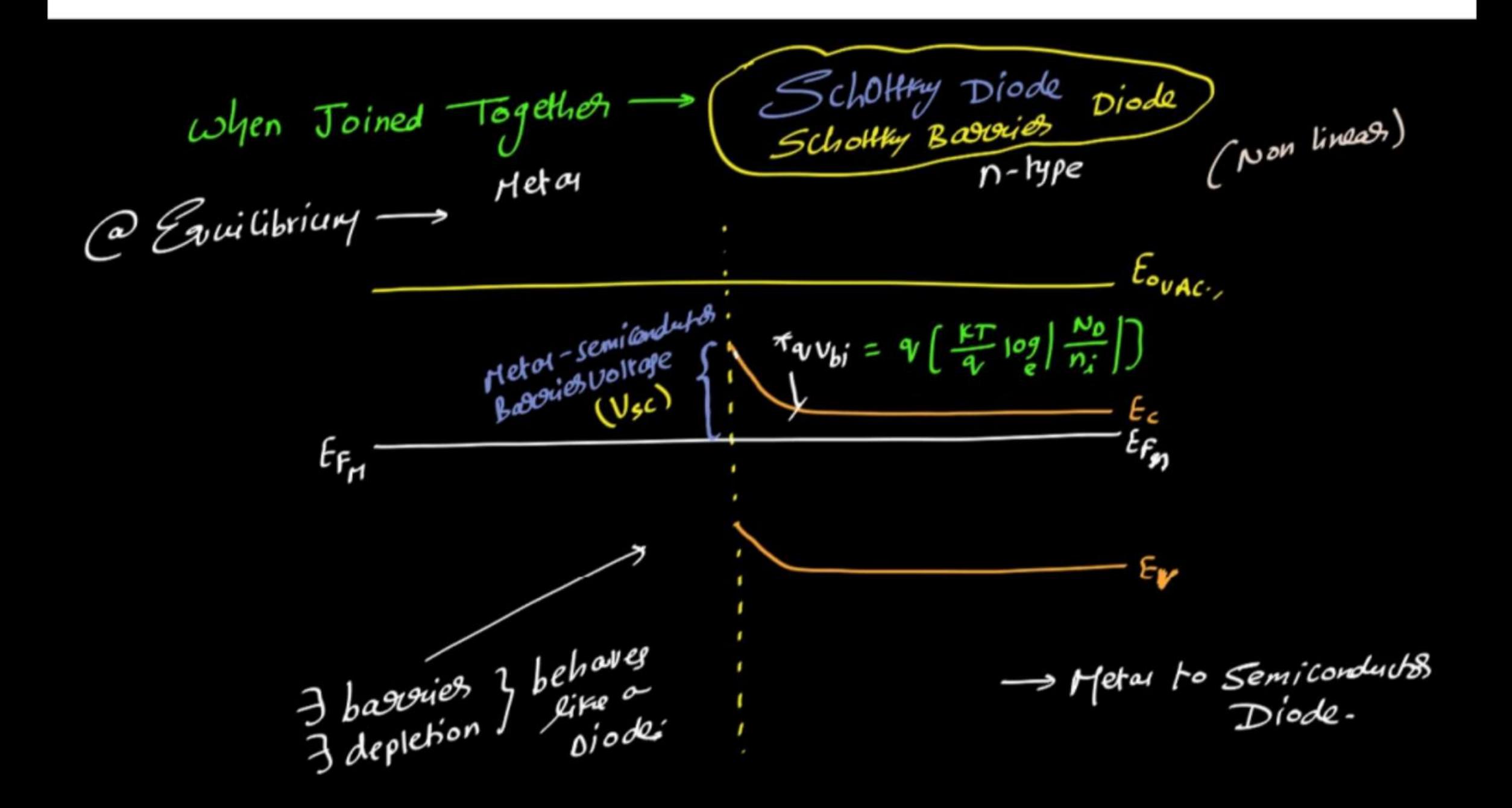


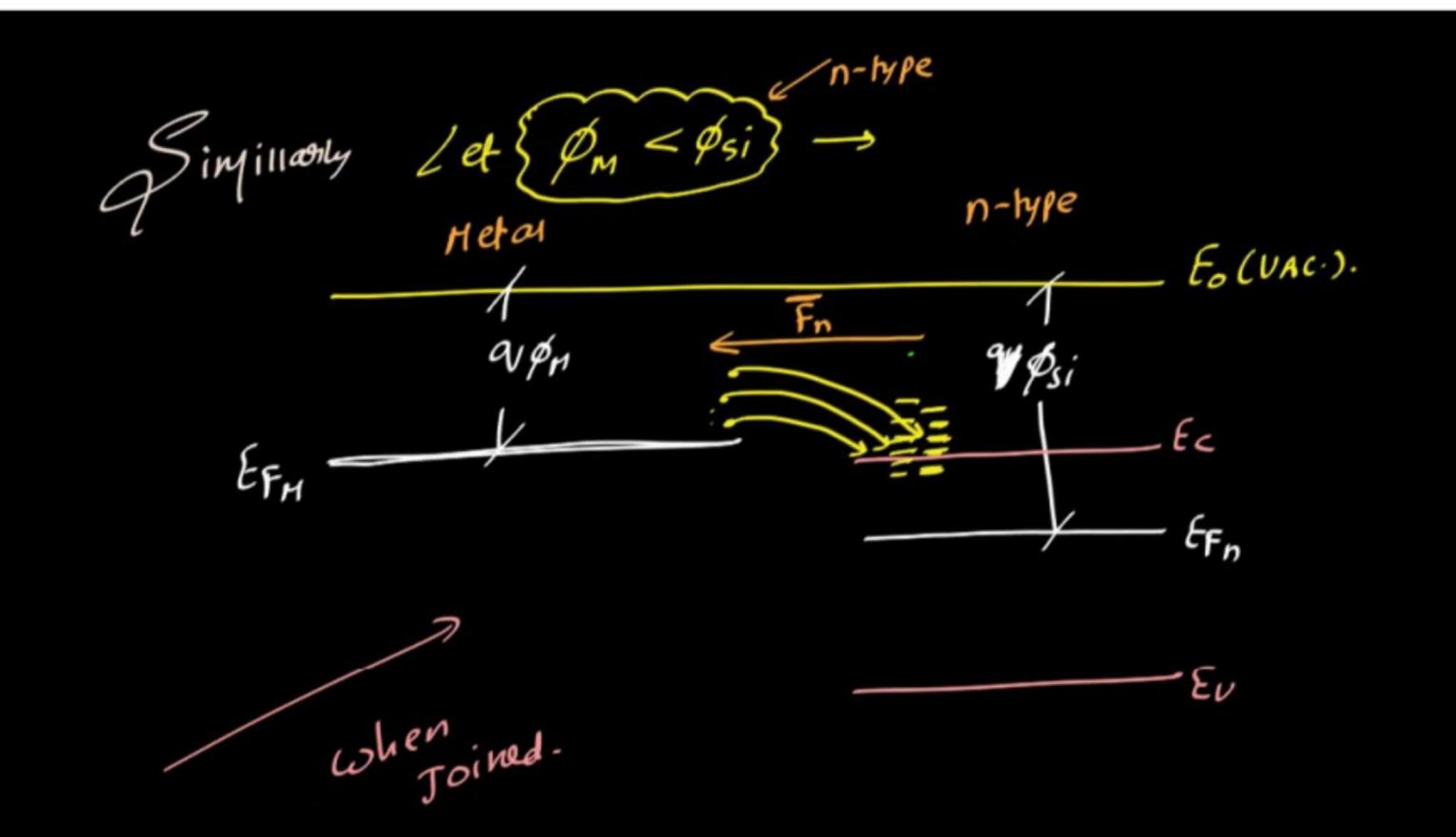
- e energy will be filled up to fermi level hence conductors need work function to bring e energy to vacuum.
- Similarly metal contacts are very important to make conduction from S.C to be propagated to external world.
- Metal like titanium, platinum, gold mix etc. will be used as metal contacts.

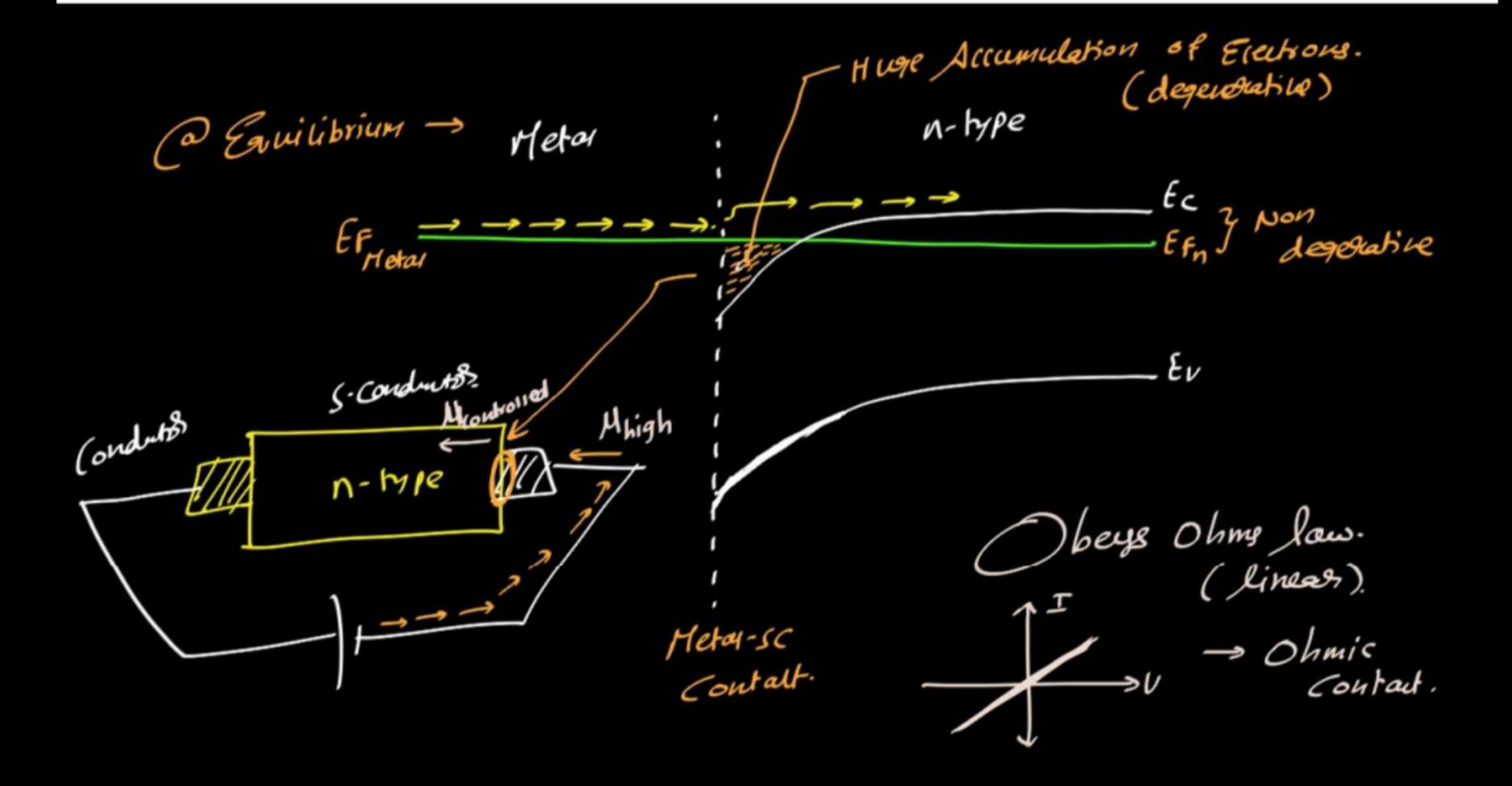




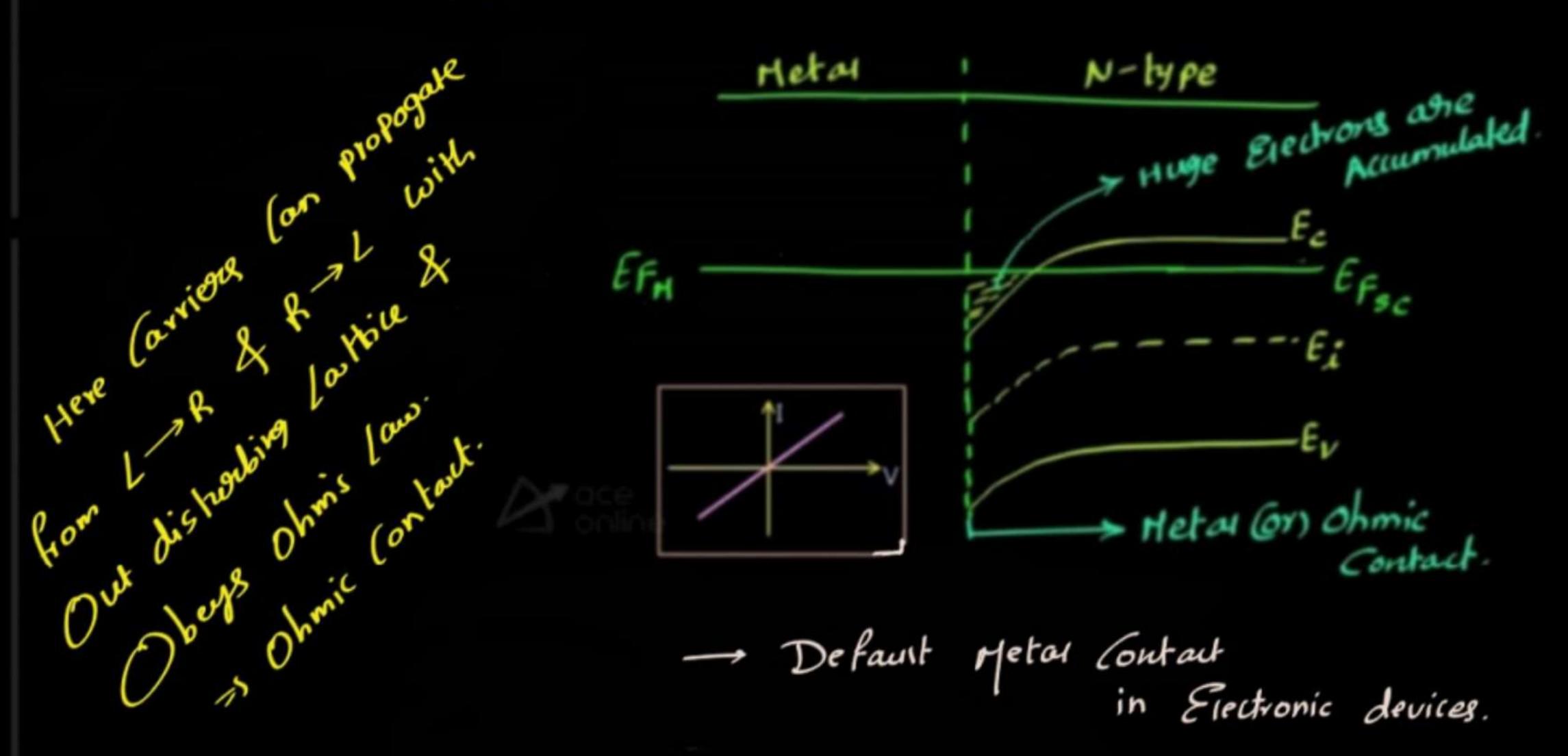
when Join & n-type. Eovac. EFM Ev







NOW Let &M < PSi ->



Hence from Above Analysis ->

Metal N-type

on < psi - Ohmic

on > psi - Schottky

on > psi - Schottky